

## **AMENDMENTS TO THE CLAIMS**

The following listing of claims will replace all prior versions and listings of claims in the application.

### **LISTING OF CLAIMS**

1. – 14. (cancelled)

15. (currently amended) The[[A]] method for manufacturing a structural member according to Claim 21, wherein characterized in that said water-repellent structure is manufactured by use of a photolithography method and an etching method.

16. – 17. (cancelled)

18. (currently amended) The[[A]] method for manufacturing a structural member according to Claim 15, wherein characterized in that said etching method is an anisotropic wet etching method.

19. – 20. (cancelled)

21. (currently amended) A method of making a water-repellant structural member formed of a single crystal silicon substrate, the method comprising:

forming irregularities on an external surface of the member, said irregularities including having protrusion portions and recessed portions, and

controlling the forming step formation of the protrusion portions so that:

      said protrusions to have a substantially uniform height with an evenness of height which is .5 times a width of one of the group selected from the protrusion portions and the recess portions, and a top surface width of the protrusions is in a range of 1 to 10  $\mu\text{m}$ ; and

said recesses have an upper opening width in a range of 1 to 10  $\mu\text{m}$  so  
that any droplet minimally falls in any of said recess portions and each droplet comes  
into contact with an air layer in each of said recess portions and dimensions chosen to  
repel liquid from the surface.